



Docket No.: H6808.0024/P024  
(PATENT)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:  
Hiroshi Miyai et al.

Application No.: 10/669,253

Confirmation No.: 3185

Filed: September 25, 2003

Art Unit: 2881

For: Inspection method and apparatus using an  
electron beam

Examiner: B. E. Souw

**AMENDMENT AFTER FINAL ACTION (37 C.F.R. SECTION 1.116)**

MS AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

**INTRODUCTORY COMMENTS**

This response accompanies a Request for Continued Examination filed in the referenced application. In response to the Office Action dated February 23, 2005, finally rejecting claims 1-14, please amend the above-identified U.S. patent application as follows:

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 7 of this paper.